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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/736,580	12/17/2003	Tatsuhiko Ema	04329.2677-01	4483
22852	7590 02/23/2005		EXAM	INER
FINNEGAN, HENDERSON, FARABOW, GARRETT & DUNNER LLP 901 NEW YORK AVENUE, NW			TADESSE, YEWEBDAR T	
			ART UNIT	PAPER NUMBER
WASHINGT	WASHINGTON, DC 20001-4413			
			DATE MAILED: 02/23/2005 .	

Please find below and/or attached an Office communication concerning this application or proceeding.

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	Application No.	Applicant(s)
	10/736,580	EMA ET AL.
Office Action Summary	Examiner	Art Unit
	Yewebdar T Tadesse	1734
The MAILING DATE of this communication app Period for Reply	pears on the cover sheet with the	correspondence address -
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.1: after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a reply - If NO period for reply is specified above, the maximum statutory period of Failure to reply within the set or extended period for reply will, by statute Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply be till y within the statutory minimum of thirty (30) day will apply and will expire SIX (6) MONTHS from to become ABANDONE	nely filed /s will be considered timely. If the mailing date of this communication. ED (35 U.S.C. § 133).
Status		
Responsive to communication(s) filed on      This action is FINAL. 2b)⊠ This      Since this application is in condition for alloware closed in accordance with the practice under E	s action is non-final.  nce except for formal matters, pr	
Disposition of Claims		
4) ☐ Claim(s) 17-19 is/are pending in the application 4a) Of the above claim(s) is/are withdray 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) 17-19 is/are rejected. 7) ☐ Claim(s) is/are objected to. 8) ☐ Claim(s) are subject to restriction and/or	wn from consideration.	
Application Papers		
9) The specification is objected to by the Examine 10) The drawing(s) filed on is/are: a) acc Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the Example 11.	cepted or b) objected to by the drawing(s) be held in abeyance. Setion is required if the drawing(s) is ol	e 37 CFR 1.85(a). ojected to. See 37 CFR 1.121(d).
Priority under 35 U.S.C. § 119		
<ul> <li>12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of:</li> <li>1. Certified copies of the priority document</li> <li>2. Certified copies of the priority document</li> <li>3. Copies of the certified copies of the priority application from the International Burea</li> <li>* See the attached detailed Office action for a list</li> </ul>	ts have been received. ts have been received in Applicat prity documents have been receiv u (PCT Rule 17.2(a)).	ion No ed in this National Stage
Attachment(s)		
<ol> <li>Notice of References Cited (PTO-892)</li> <li>Notice of Draftsperson's Patent Drawing Review (PTO-948)</li> <li>Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date 12/17/2003.</li> </ol>	4) Interview Summar Paper No(s)/Mail I 5) Notice of Informal 6) Other:	

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## **DETAILED ACTION**

## Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) The invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 2. Claims 17-18 are rejected under 35 U.S.C. 102(b) as being anticipated by Tateyama et al (US 5,965,200). As to claim 17, Tateyama et al discloses (see Figs 2-3) a film forming apparatus comprising a dispenser nozzle (solution supply nozzle 22) arranged to face a target substrate to be processed so as to supply a chemical solution to the target substrate (G); a suction nozzle (23) arranged to face the target substrate for sucking a solvent vapor (developing solution capable of being a mixture of solvent vapor) on a liquid film formed on the target substrate by the supply of a chemical solution from the dispenser nozzle (22), a first moving section for relatively moving the target substrate and the dispenser (moving mechanism 25 for moving dispenser nozzle 22, and spin chuck 21 moving the substrate, relatively moving to each other); and a second moving section for relatively moving the target substrate and the suction nozzle (moving mechanism 25 for moving the suction nozzle 23 and spin chuck 21 moving the substrate, relatively moving to each other). With respect to claim 18, Tateyama et al. discloses (see Fig 7) a supply nozzle (gas getting nozzle 45) for supplying a flow of gas to the liquid film formed on the target substrate.

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Claims 17-18 are rejected under 35 U.S.C. 102(b) as being anticipated by JP 04-3. 181143. As to claim 17, JP'143 discloses (see Fig 1 and English translated Abstract) a specimen recovering apparatus capable of forming a film comprising a dispenser nozzle (vapor and water nozzles 3 and 5 respectively) arranged to face a target substrate to be processed so as to supply a chemical solution to the target substrate (11); a suction nozzle (2) arranged to face the target substrate for sucking a solvent vapor (reaction solution including vapor) on a liquid film formed on the target substrate by the supply of a chemical solution from the dispenser nozzle (vapor and water nozzles 3 and 5 respectively), a first moving section for relatively moving the target substrate and the dispenser (rocking and rotating stage moving the substrate relative to the nozzles 3 and 5); and a second moving section for relatively moving the target substrate and the suction nozzle (suction nozzle moving from point B to an A point relative to the substrate). With respect to claim 18, JP'143 discloses (see Fig 1 and English translated Abstract) a supply nozzle (nitrogen gas bubbling nozzle 4a) for supplying a flow of gas to the liquid film formed on the target substrate.

## Claim Rejections - 35 USC § 103

- 4. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

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5. This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

6. Claim19 is rejected under 35 U.S.C. 103(a) as being unpatentable over Tateyama et al (US 5,965,200) as applied to claim 1 above, and further in view of Tanaka et al (US 6,692,165). Tateyama et al discloses (see Fig 4 and column 6, lines 36-40) that the length of the head suction nozzle is the same as the width of the substrate. However, the length of the suction port of the suction nozzle larger than the diameter of the substrate is not taught in Tateyama et al. Tanaka et al discloses (see Fig 8 and column 12, lines 57-65) the longitudinal suction width L (210 mm) nozzle 41 larger than the diameter of the substrate (8 in =203.2 mm). It would have been obvious to one of ordinary skill in the art at the time the invention was made to include a suction port of a suction nozzle having a length larger than the diameter of the substrate in Tateyama et al as to fully apply suction force by completely covering the face of the substrate.

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7. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Yewebdar T Tadesse whose telephone number is (571) 272-1238. The examiner can normally be reached on Monday-Friday 8:00 AM-4: 30 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Chris Fiorilla can be reached on (571) 272-1187. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

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CHRIS FIORILLA SUPERVISORY PATENT EXAMINER

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